

Substitute Form PTO-1449
(Modified)U.S. Department of Commerce
Patent and Trademark OfficeAttorney's Docket No.
09712-341001Application No.
10/795,808**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

Applicant
Peter de Groot et al.Filing Date
March 8, 2004Group Art Unit
2877

(37 CFR 1.98(b))

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
MAL	AA	4,660,980	04/1987	Takabayashi et al.			
	AB	4,818,110	04/1989	Davidson			
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	AJ	6,259,521	07/10/2001	Miller et al.			
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	AS	2004/0085544	05/06/2004	de Groot et al.			
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	AU	2005/0057757	3/17/2005	de Lega et al.			
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	AY	2005/0088663	4/28/2005	de Groot et al.			
	AZ	2005/0146727	7/7/2005	Hill			
MAL	AAA	2005/0237534	10/27/2005	Deck			

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	BC						

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							Yes	No
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	BI							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
MAL	BJ	C. Akcay et al., "Spectral shaping to improve the point spread function in optical coherence tomography", <u>Optics Letters</u> , Vol. 28, No. 20, pp. 1921-1923 (October 15, 2003)
↓	BK	R.M.A. Azzam et al., "Reflection and Transmission of Polarized Light by Stratified Planar Structures", <u>Ellipsometry and Polarized Light</u> , Elsevier Science B.V. ISBN 0 444 87016 4 (Paperback) pp. 267-363 (1987)
	BL	R.M.A. Azzam et al., "Ellipsometric function of a film-substrate system: Applications to the design of reflection-type optical devices and to ellipsometry", <u>Journal of the Optical Society of America</u> , Vol. 5, No. 3, pp. 252-260
	BM	M. Bashkansky et al., "Signal Processing for Improving Field Cross-correlation Function in Optical Coherence Tomography", <u>Supplement to Optics & Photonics News</u> , 9(5) (May, 1998)
	BN	Berman et al., "Review of In Situ & In-line Detection for CMP Applications", <u>Semiconductor Fabtech - 8th Edition</u> , pp. 267-274
	BO	A. Bosseboeuf et al., "Application of microscopic interferometry techniques in the MEMS field", <u>Proc. SPIE</u> , 5145, pp. 1-16 (2003)
↓	BP	M. Davidson et al., "An Application of Interference Microscopy to Integrated Circuit Inspection and Metrology", <u>Proceedings of SPIE</u> , Vol. 775, pp. 233-247 (1987)
MAL	BQ	J.E. Greivenkamp, "Generalized data reduction for heterodyne interferometry", <u>Opt. Eng.</u> , Vol. 23 No.4, pp. 350-352 (July/August 1984)

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Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
MAL	CA	P de Groot et al., "Signal modeling for low coherence height-scanning interference microscopy", <u>Applied Optics</u> , Vol. 43 No. 25, pp. 4821-4830 (September 1, 2004)
	CB	P. de Groot, "Derivation of algorithms for phase-shifting interferometry using the concept of a data-sampling window", <u>Appl. Opt.</u> , 34(22), p. 4723-4730 (1995)
	CC	P. de Groot et al., "Signal modeling for modern interference microscopes", <u>SPIE Proceedings</u> , 5457-4 (2004)
	CD	Peter de Groot et al., "Determination of fringe order in white-light interference microscopy", <u>Appl. Opt.</u> , 41(22) pp. 4571-4578 (2002)
	CE	P.A. Flourmoy et al., "White-light interferometric thickness gauge", <u>Appl. Opt.</u> , 11(9), pp. 1907-1915 (1972)
	CF	G. Hausler et al., "Coherence Radar and Spectral Radar – New Tools for Dermatological Diagnosis", <u>Journal of Biomedical Optics</u> , Vol. 3, No. 1, pp. 21-31 (January, 1998)
	CG	R.D. Holmes et al., "Scanning microellipsometry for extraction of true topography", <u>Electronics Letters</u> , Vol. 31, No. 5, pp. 358-359 (March 2, 1995)
	CH	Seung-Woo Kim et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
	CI	Kieran G. Larkin, "Efficient nonlinear algorithm for envelope detection in white light interferometry", <u>J. Opt. Soc. Am A4</u> , pp. 832-843 (1996)
	CJ	Kujawinska, Malgorzata, "Spatial Phase Measurement Methods", <u>Interferogram Analysis: Digital Fringe Pattern Measurement Techniques</u> , IOP Publishing Ltd. 1993, pp. 141-193
	CK	Lee et al., "Profilometry with a coherence scanning microscope", <u>Appl. Opt.</u> , 29(26), pp. 3784-3788 (1990)
	CL	I. Lee-Bennett, "Advances in non-contacting surface metrology", <u>OF&T Workshop</u> , paper OTuC1 (2004)
	CM	K. Leonhardt et al., "Micro-Ellipso-Height-Profilometry", <u>Optics Communications</u> , Vol. 80, No. 3, 4, pp. 205-209 (January 1, 1991)
	CN	Y. Liu et al., "Common path interferometric microellipsometry", <u>SPIE</u> , Vol. 2782, pp. 635-645 (1996)
	CO	Lyakin et al., "The interferometric system with resolution better than coherence length for determination of geometrical thickness and refractive index of a layer object", <u>Proceedings of the SPIE – The International Society for Optical Engineering SPIE-INT. Soc. Opt. Eng USA</u> , Vol. 4956, pp. 163-169 (July, 2003)
	CP	C.J. Morgan, "Least-Squares estimation in phase-measurement interferometry", <u>Apt. Let.</u> , 7(8), pp. 368-370 (1982)
	CQ	Ngoi et al., "Phase-shifting interferometry immune to vibration", <u>Applied Optics</u> , Vol. 40, No. 19, pp. 3211-3214 (2001)
	CR	A.V. Oppenheim et al., "10.3: The time-dependent Fourier Transform", <u>Discrete-Time Signal Processing</u> , 2 nd Edition, pp. 714-722 (Prentice Hall, New Jersey, 1999)
✓	CS	M.C. Park et al., "Direct quadratic polynomial fitting for fringe peak detection of white light scanning interferograms", <u>Opt. Eng.</u> , 39(4), pp. 952-959 (2000)
MAL	CT	W.H. Press et al., "Linear Correlation", <u>Numerical Recipes in C</u> , Cambridge University Press, 2 nd Edition, pp. 636-639 (1992)

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MAL	DA	P. Sandoz et al., "Optical implementation of frequency domain analysis for white light interferometry", <u>Proceedings SPIE</u> , Vol. 2545, pp. 221-228 (June, 1995)
↓	DB	P. Sandoz et al., "High-resolution profilometry by using phase calculation algorithms for spectroscopic analysis of white-light interferograms", <u>Journal of Modern Optics</u> , Vol. 43, No. 4, pp. 701-708 (1996)
	DC	P. Sandoz et al., "Processing of white light correlograms: simultaneous phase and envelope measurements by wavelet transformation", <u>SPIE</u> , 3098, pp. 73-82 (1997)
	DD	U. Schnell et al., "Dispersive white-light interferometry for absolute distance measurement with dielectric multilayer systems on the target", <u>Optics Letters</u> , Vol. 21, No. 7, pp. 528-530 (April, 1996)
	DE	J. Schwider et al., "Dispersive interferometric profilometer", <u>Optics Letters</u> , Vol. 19, No. 13, pp. 995-997 (July, 1994)
	DF	C.W. See et al., "Scanning optical microellipsometer for pure surface profiling", <u>Applied Optics</u> , Vol. 35, No. 34, pp. 6663-6668 (December 1, 1996)
	DG	M. Totzeck, "Numerical simulation of high-NA quantitative polarization microscopy and corresponding near-fields", <u>Optik</u> , Vol. 112, No. 9, pp. 399-406 (2001)
	DH	R. Tripathi et al., "Spectral shaping for non-Gaussian source spectra in optical coherence tomography", <u>Optics Letters</u> , Vol. 27, No. 6, pp. 406-408 (2002)
MAL	DI	D. Willenborg et al, "A novel micro-spot dielectric film thickness measurement system", <u>SPIE</u> , Vol. 1594, pp. 322-333 (1991)
	DJ	

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